

Electro-Optic Modulators for R-FLICS based on a Self-Assembled Superlattice (SAS)

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- 1. Introduction
- 2. Self-Assembled Superlattice (SAS) Materials
- 3. EO Modulator Device Design & Fabrication
- 4. Switching Voltage Measurements
- 5. Future Work





Motivation

Next-Generation EO Modulators

- LiNbO₃ EO modulators with 10Gbit/sec data transfer rates are being used in current optical communication systems.
- Communication industries have identified 40 Gbit/sec as the requirement for next-generation EO modulators with below 5 volt to be compatible with integrated RF driving circuits.
- •RF Photonics applications require switching voltage below 1 V.
- Current EO modulators are based on bulk-grown LiNbO₃ crystals and have reached close to their performance limits.
 - Novel approaches are required to realize the next-generation of EO modulators with bandwidths of 40 GHz and above.





Our Approach

Materials

Organic: Self-Assembled Superlattices

Novel Device Design

Strongly Confined Thin-Film Waveguide





Advantages

Materials

Polymer: Self-Assembled Superlattices

Molecular engineering of hyperpolarizability -> High EO coefficient $(r_{33} \ge 100 \text{pm/V})$

Low dielectric constant -> Higher Bandwidth

No Poling required -> More stable, Simple design

Tunable refractive index (n=1.5~1.75) -> Better Confinement

Novel Device Design

Strongly Confined Thin-Film Waveguide

Higher E-Field strength, better opto-rf field-overlap
-> Lower switching voltage (< 5V)
Reduced opto-rf Velocity-mismatch
-> Higher Bandwidth (> 40GHz)





Goals of NWU's R-FLICS Program

Next-Generation SAS EO Modulators

- I. Develop growth processes for intrinsically polar organic selfassembled superlattices (SAS)
 - Electric field poling unnecessary
 - Very large r₃₃, low M_→.
- II. Develop capability to tune materials properties
 - r₃₃, n, M, loss
- III. Develop fabrication methodologies to turn SAS materials into high-performance EO modulators.
 - Lithography, cladding, substrate generality
- IV. Fabricate and test self-assembled electro-optic modulators.
 - Minimize V_{π} , loss



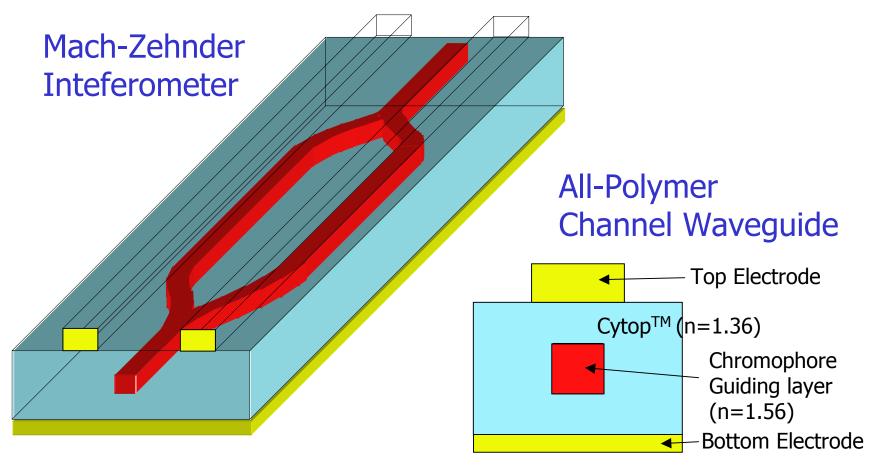
EO Modulators: Figures of Merit

	LiNbO ₃	Poled EO Polymers	Self-Assembled Superlattice
EO coefficient (pm/V)	31	10-75	30-200
Dielectric constant, ε	28	4	6
Refractive Index n	2.2	1.6	1.6
n³r (pm/V)	248	150	120-820
n³r/ε	8.7	40	20-820





Optical Waveguide Structure







Design Motifs for Molecular/Polymer Electro-Optic Materials

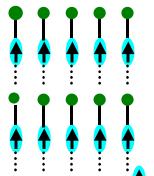
Poled Host-Guest



Poled, Functionalized, Crosslinked



Chromophoric LB Film

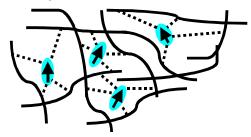


= Chromophore Module

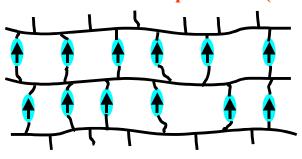
Poled and Functionalized



Poled, Crosslinkable Matrix



Self-Assembled Superlattice (SAS)

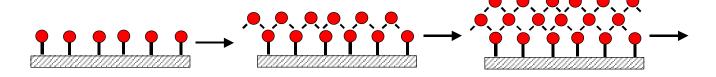




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Materials Construction via Layer-by-Layer Siloxane Self-Assembly



Condensation Chemistry

Characteristics

Å-Precise Self-Limiting Build-Up of Cross-Linked MultilayersRobust, Conformal, Smooth, Adherent, Pin HoleFree
Applicable to Many Molecular Building Blocks

Characterization

SPM, X-Ray Reflectivity, Standing Wave X-Ray, Ellipsometry, Optical Spectroscopy, Cyclic Voltammetry, Advancing Contact Angle, TGA, SHG Response Electroluminescence





Electronic Structure Theory in Materials Development

Correction Vector/Sum-Over-States ZINDO Calculations

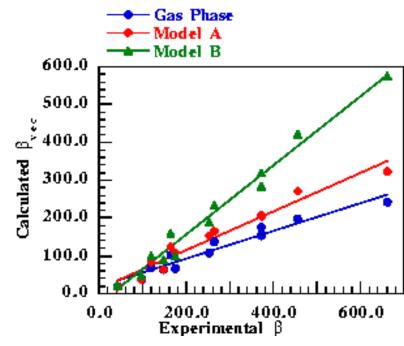
Attractions

- Target New Molecular Architectures For Synthesis
- Test New Response Mechanisms
- Understand Mechanisms,
 Frequency Dependence

 $\mu B(0.65 \text{ eV}) = 200.000 \times 10^{-48} \text{ esu}$

Challenges

- Environmnetal Effects
- Metal-Organic Structures
- Open Shell Molecules, Excited States
- •Luminescent Electron-Hole Recombination



Ratner, Fragala, Di Bella





What are Self-Assembled Electro-Optic Materials?

- Environmentally Stable, Adherent Thin Films
- Grown from Designed Building Blocks
- Manufacturable by Automated Dipping Techniques
- Northwestern Patent Coverage

Attraction for E-O Modulators

- Intrinsically Polar
 Electric Field Poling Unnecessary
- -Large E-O Coefficients Possible \rightarrow Low Operating Voltages $r_{33} = 30 500 \text{ pm/V}$
- Grown on Range of Substrates
 SiO₂, GaAs, ITO, Plastics, Spin-on-Glass
- Broad Tunable Transparency Window



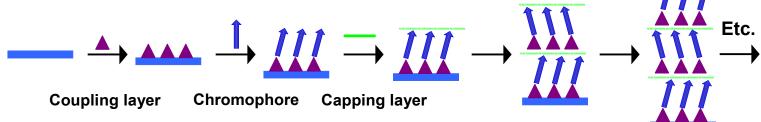


STRUCTURES AND MULTILAYER GROWTH BY MOLECULAR SELF-ASSEMBLY

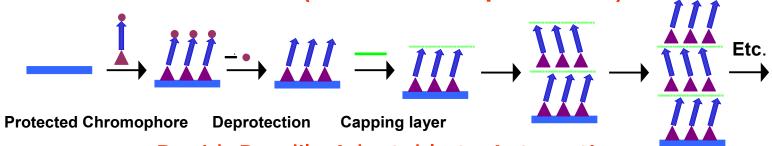
- Programmed Polar Microstructure
- Tailored Building Blocks
- Compatible with Soft Lithography
- $n^3 r/\epsilon = 20-140 \text{ pm/V}$

- Synthetic Scope, Fidelity, Scalability
- Tune λ , β , r
- Templated Growth, Device Integration
- Microstructure, Loss

I. First Generation



II. Second Generation (Protection-Deprotection)



Rapid. Readily Adaptable to Automation

Robust, Adherent, Smooth, Structurally, Regular Siloxane Networks





Construction of Chromophoric Multilayers by Molecular Layer Epitaxy

First Generation Self-Assembly

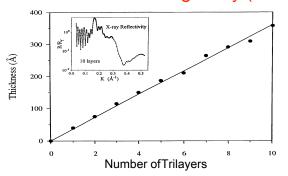
- 1. Rapid Topotactic Multilayer Growth
- 2. Intrinsically Acentric (No Poling Required)
- 3. Very High Structural Regularity
- 4. Very Large $\chi^{(2)}$ Response

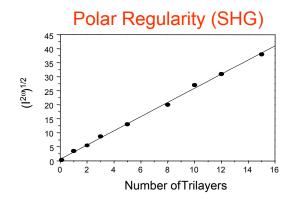




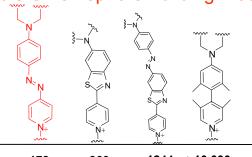
First Generation Self-Assembled Electro-Optic Materials

Microstructural Regularity (XRR)

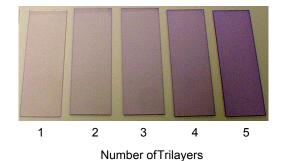




Versatile Chromophore Building Blocks



Samples of Self-Assembled Films	
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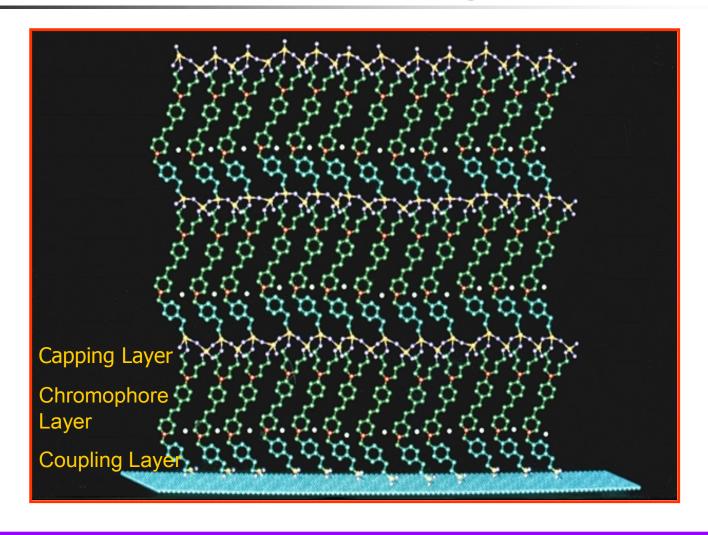


β (0.65 eV)calcd.	178	360	1244	>10,000
(10 ⁻³⁰ cm ⁵ esu ⁻¹) λ _{max} calcd (nm)	572	498	510	610
Film r ₃₃ , ω _o =1064 nm (pm/V)	56	125	180	>2000
Generation Method	1,2	1	2	





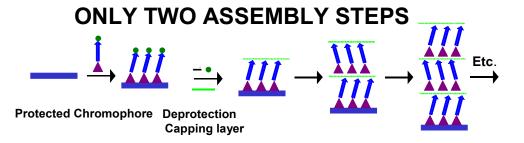
Molecular Modeling of SAS

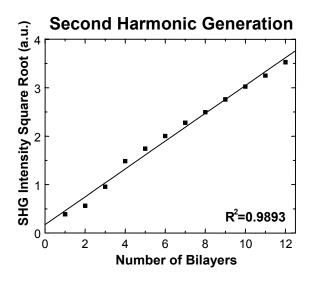


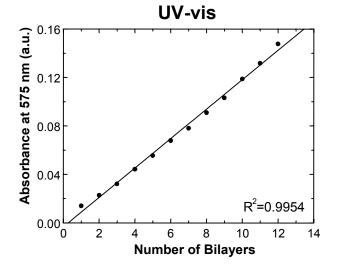




Second Generation: Combining the Deprotection and the Capping Step



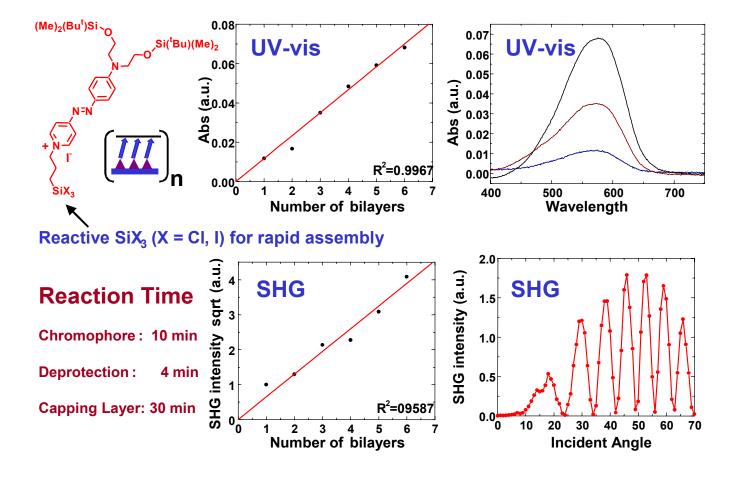








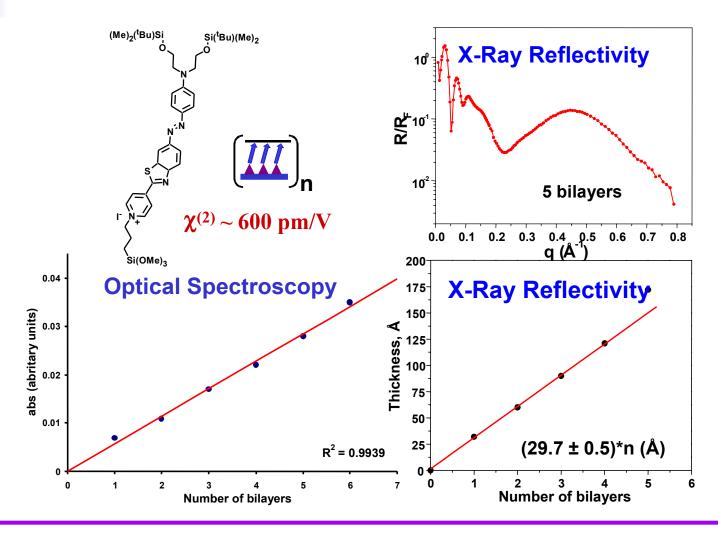
2nd Generation Self-Assembly (Protection-Deprotection)







2nd Generation Self-Assembly: Results II

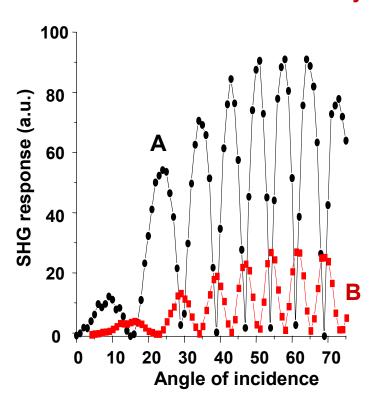


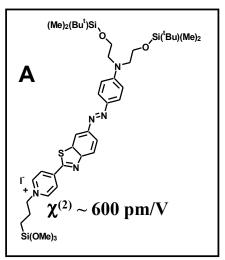




Comparison of NLO Properties of Thin Films

Second Generation Self-Assembly

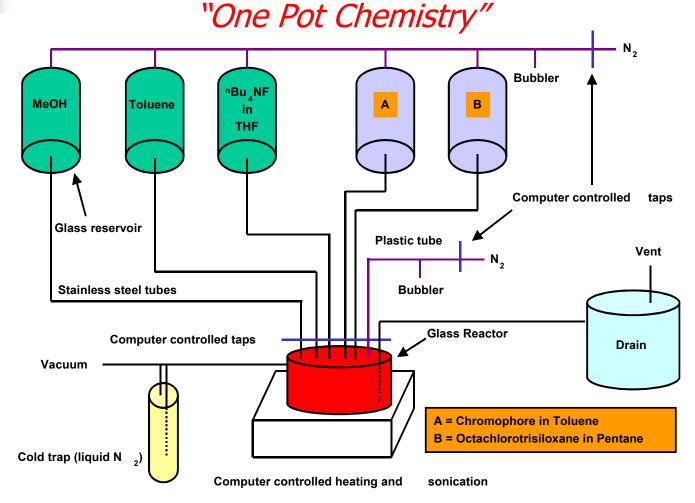








2nd Generation Self-Assembly: Growth Method





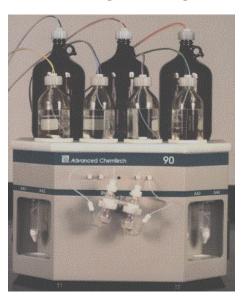


Automation Tools for Self-Assembly

MODIFIED BIO SLIDE STAINER/DIPPER



MODIFIED SOLID PHASE PEPTIDE SYNTHESIZER



ALLOW PROGRAMMED LAYER-BY-LAYER FABRICATION



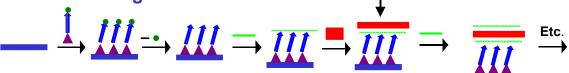


Development of Growth Process



Metal Oxide Layer

SA-Films with High Refractive Index



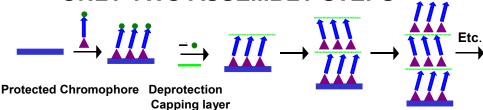
Protected Chromophore Deprotection Capping layer Metal Complex Capping layer

For First and Second Generation Self-Assembly

'BIFUNCTIONAL HYBRID STRUCTURE'

Second Generation: Combining the Deprotection and the Capping Step

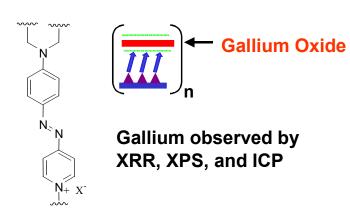
ONLY TWO ASSEMBLY STEPS

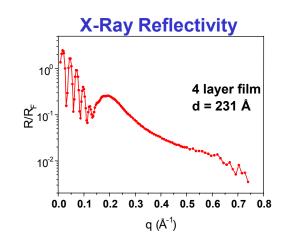




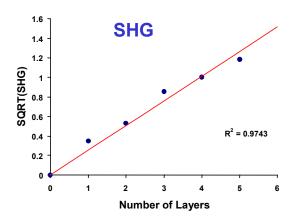


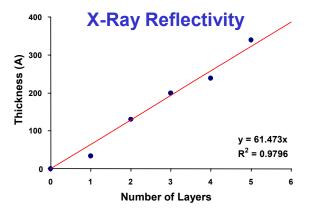
2nd Generation Self-Assembly with High Refractive Index SA Films





Gallium oxide formation in 30 min at r. t. from commercially available precursor

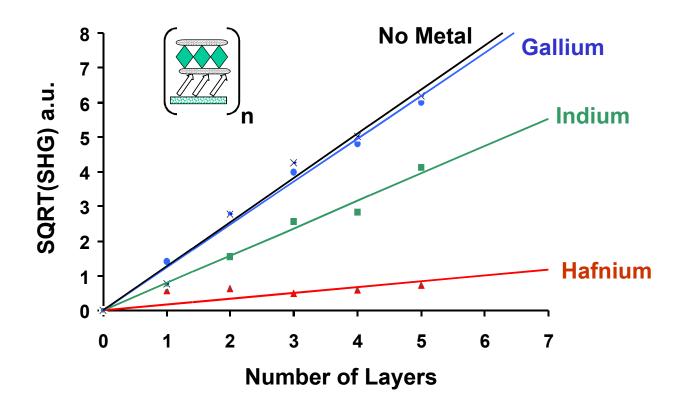








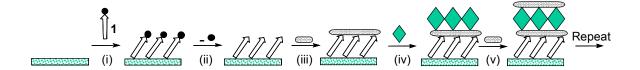
Second Harmonic Generation @1064nm

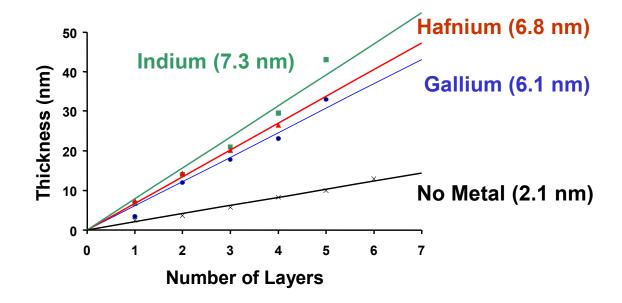






X-Ray Reflectivity (XRR)



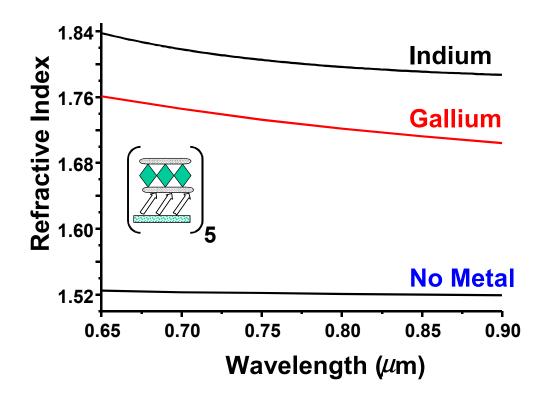






Index of Refraction Measurements

Of SASs with Various Metal-Oxides



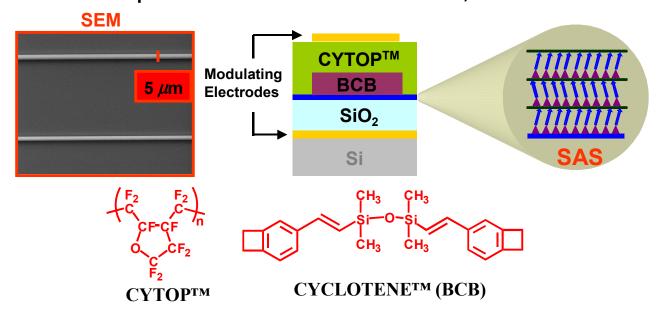


ELECTRO-OPTIC MATERIALS SYNTHESIS BY SELF-ASSEMBLY

• Tune λ, β, r

- Programmed Polar Microstructure
 Synthetic Scope, Scalability
- Tailored Building Blocks
- Compatible with Soft Lithography Templated Growth, Device Integration
- $n^3 r/\epsilon = 20-140 \text{ pm/V}$

Microstructure, Loss



First Self-Assembled EO Modulator

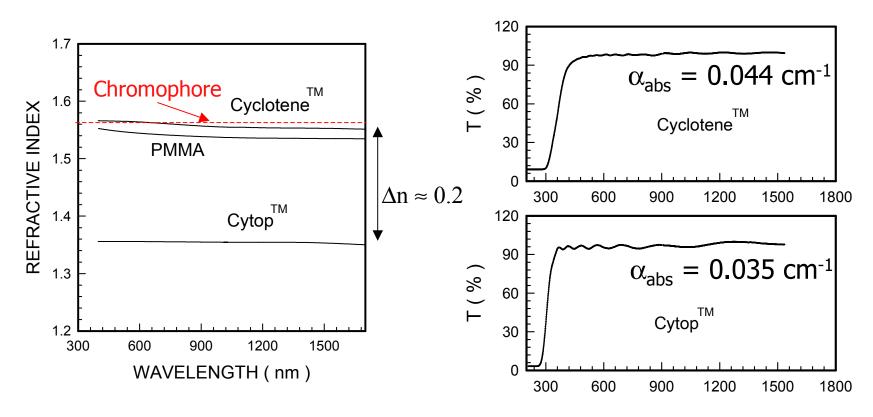




Optical Properties of Polymers

Index of Refraction

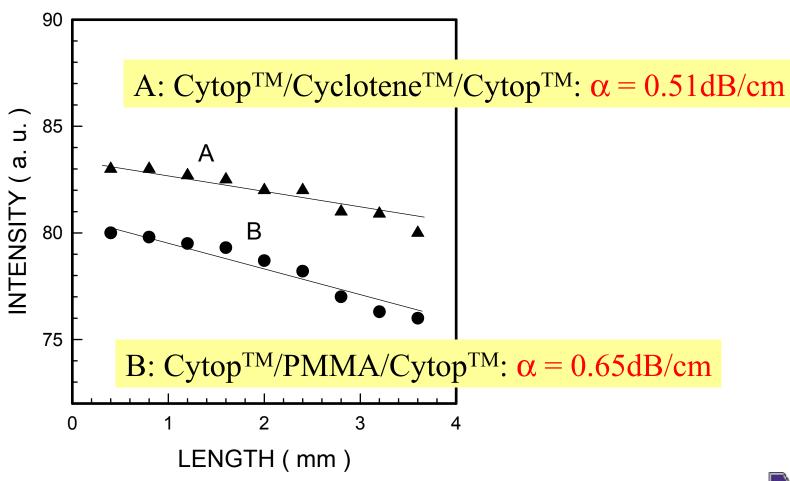
Transmission Spectra







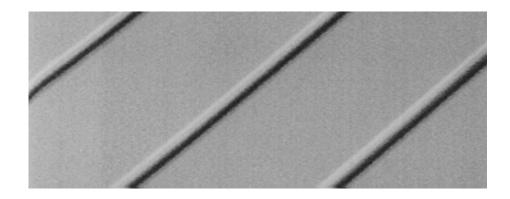
Propagation Loss Measurements

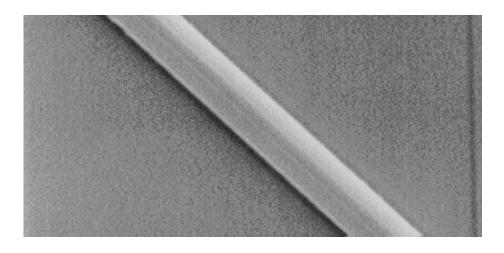






SEM Images of Waveguides

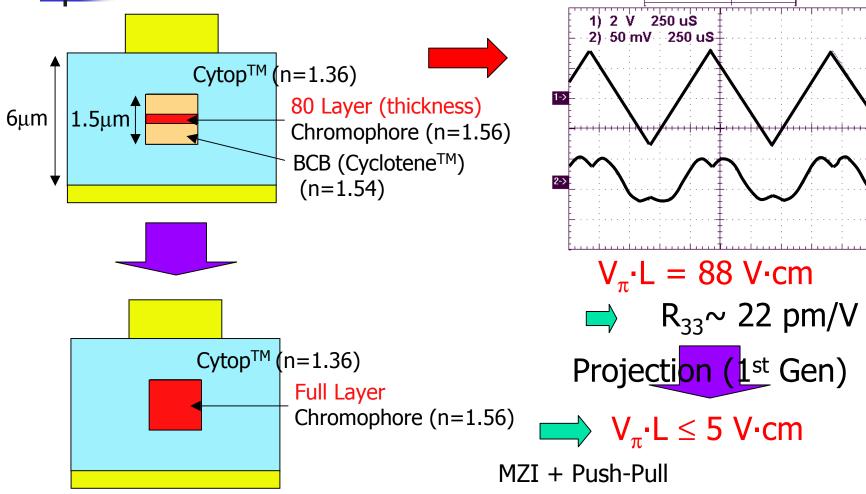








Current Prototype Modulator







Device Optimization

Index Tuning of SAS

Molecular engineering gives extra degrees of freedom in varying chromophore layer index of refraction

Goal of Optimization:

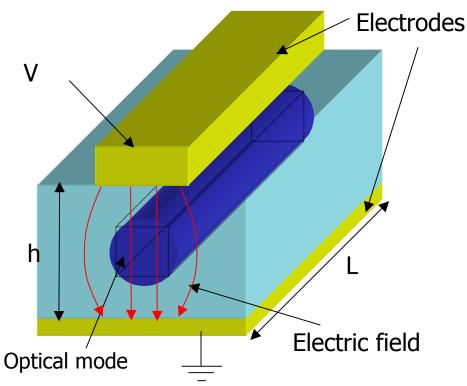
- 1. Lower Switching Voltage
- 2. Higher Modulation Bandwidth
- 3. Better Confinement of Light





Switching Voltage (V_{π})

$$V_{\pi} \cdot L = \frac{\lambda h}{2n_{eff-opt}^{3} r \Gamma_{e} \Gamma_{o}}$$



 $n_{\it eff-opt}$:effective optical index

? :EO coefficient

 Γ_{α} :optical overlap factor

 Γ_{ρ} :electrical overlap factor





Modulation Bandwidth

$$H(f) = e^{-\frac{\alpha L}{2}} \left[\frac{\sinh^2(\frac{\alpha L}{2}) + \sinh^2(\frac{\xi L}{2})}{\left(\frac{\alpha L}{2}\right)^2 + \left(\frac{\xi L}{2}\right)^2} \right]^{\frac{1}{2}}$$

$$\xi = 2\pi f \frac{n_{RF} - n_{opt}}{c}$$
 : Velocity mismatch between RF and optical waves

Determines "Walk-off bandwidth"

$$\alpha_{\rm RF}$$
 : RF attenuation coefficient $\propto \sqrt{f}$

Induces RF power loss along the electrodes





How Higher Index Improves the Performance

1. Lower switching voltage

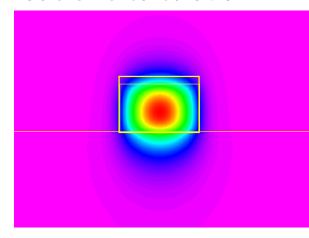
- $V_{\pi} \propto 1/n^3 r$
- Higher n -> Smaller optical mode size
 - -> Reduced Electrode separation
 - -> Higher E-field strength
- 2. Fewer active layer needed by reduced optical mode size



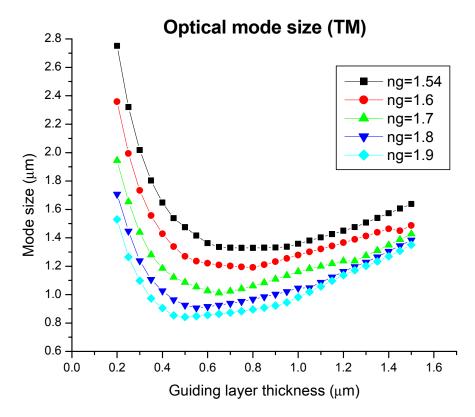


Optical Mode Calculation

Beam Propagation Method: Mode size calculation



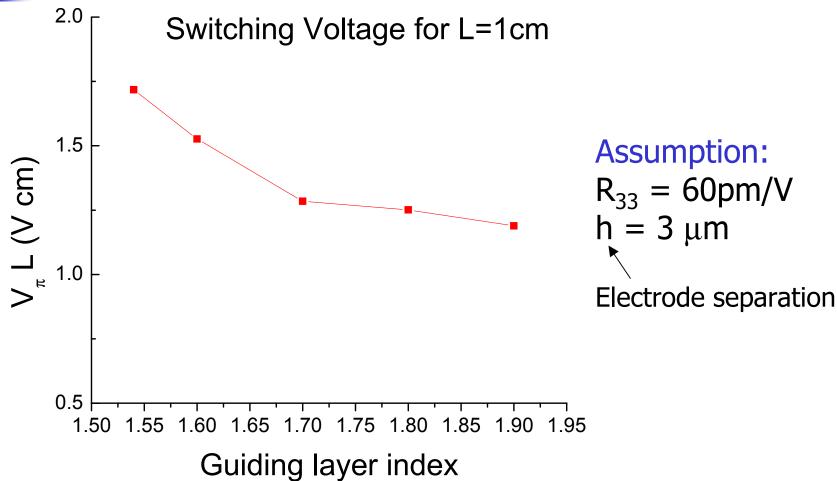
Effective Index Method: Optical Ovelap factor (Γ_0)







Switching Voltage vs. Guiding Layer Index







RF Simulation I

Quasi-static Finite Element Methods:



 \longrightarrow Provides C & C₀

C: Capacitance with materials present

C₀: Capacitance with air

(1) Velocity mismatch: effective RF index

$$n_{eff-opt} = \sqrt{\frac{C}{C_0}}$$

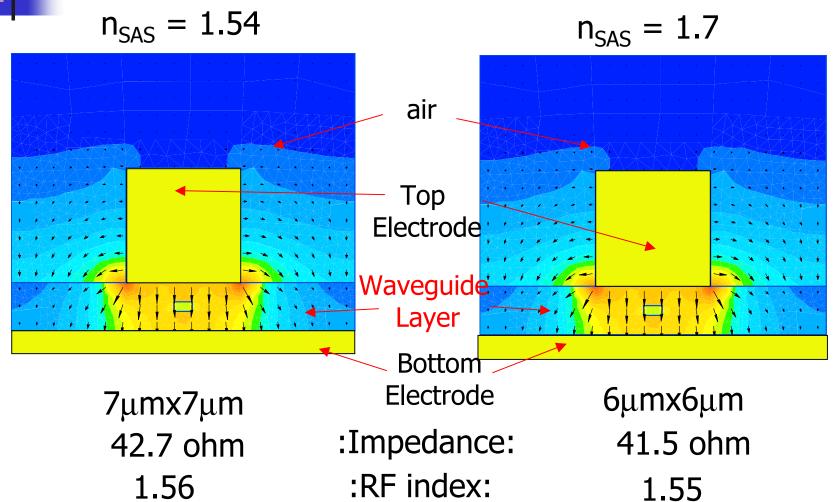
(2) Characteristic impedance:

$$Z = \frac{1}{c\sqrt{CC_0}}$$





RF Simulation II

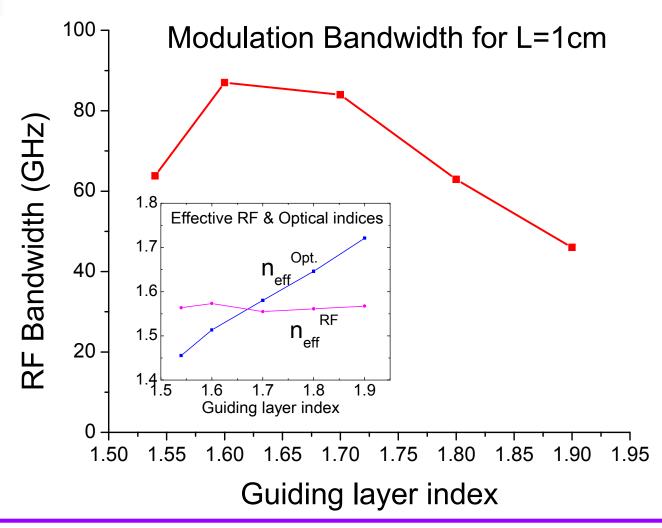


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RF Bandwidth vs. Guiding Layer Index







Most Significant Accomplishments

SAS Materials Development

- Highly efficient protection-deprotection growth technique demonstrated
 - My⁽²⁾ © 220pm/V, r₃₃ © 80pm/V
- Automated growth apparatus implemented for SAS structures
- Metal oxide layer incorporation demonstrated for index tuning







Device Development

- All polymer waveguides demonstrated with good transparencies from 350-1650nm
 - Cytop[™]/Cyclotene[™]/Cytop[™]: ©=0.5 dB/cm
- First SAS electro-optic modulators fabricated and tested
 - Simple design, $V\pi$ -L=88 V-cm
 - Route to low $V\pi$ clear: Thicker films, longer devices, advanced chromophores





Future Efforts

- Y1 Streamline growth techniques

 Tune refractive index

 All-polymer waveguide

 Fabricate first SAS modulator
- Y2 Routine automated assembly
 Grow, characterize thick active SAS structures
 Design, routinely fabricate, characterize modulators
- Y3 Incorporate "super-chromophores" in SAS structures Automated index tuning Design, routinely fabricate, characterize modulators
- Y4 Implement soft lithography to template SAS growth Demonstrate efficiently fabricated SAS modulators with $V\pi$ <1V Test modulators in various environments





Conclusions

1. Switching voltage is measured for the first time from the SAS-organic modulator:

$$V_{\pi} \cdot L = 88 \text{ V} \cdot \text{cm} \text{ for } 80 \text{ Layer}$$

- -> projected to be $V_{\pi} \cdot L \le 5 \text{ V} \cdot \text{cm}$ for a device with fully grown chromophore layer
- Device optimization simulation performed using index tuning of SAS: Higher index gives lower switching voltage

and Fewer SAS layer needed.

